

A) Amendments to the Claims:

Claim 1 (currently amended). A vacuum evaporation deposition method of the winding type in which under an atmosphere of reduced pressure, an insulating material base film is continuously fed out, cooled in close contact with a cooling roller and metal is evaporated onto said insulating material base film to deposit a metal film thereon, the method characterized in that:

before the deposition of the metal film, forming a mask pattern by depositing an oil pattern on a surface of the insulating material base film for defining a deposition region for the metal film, and charging said insulating material base film whereby said insulating material base film is thereby closely contacted with said cooling roller;

after the deposition of the metal film, applying a voltage between said metal film an auxiliary roller and said cooling roller, said auxiliary roller guiding said insulating material base film in contact with the deposited metal film, whereby said insulating material base film is closely contacted with said cooling roller and thereafter plasma-bombarding said insulating material base film between said auxiliary roller and a winding roller for taking up said insulating material base film for thereby removing electrical charge on said insulating material base film prior to take-up winding.

Claim 2 (previously presented). A vacuum evaporation deposition method of the winding type according to claim 1, in which in the step of charging said insulating material base film is performed with charged particles irradiated onto the running insulating material base film while being scanned in the width direction of said insulating material base film.

Claim 3 (previously presented). A vacuum evaporation deposition method of the winding type according to claim 2, in which said charged particles are irradiated at a time when said insulating material base film is contacted with said cooling roller.

Claim 4 (previously presented). A vacuum evaporation deposition method of the winding type according to claim 1, in which in the step of applying the voltage between the metal film and said cooling roller, a DC voltage is applied between an auxiliary roller for guiding said insulating material base film with said metal film deposited thereon and said cooling roller.

Claim 5 (previously presented). A vacuum evaporation deposition method of the winding type according to claim 4, in which the step of applying the voltage between the metal film and said cooling roller includes a step of measuring a surface potential of said metal film and another step of so controlling the applying voltage as to place said surface potential within a predetermined range.

Claim 6 (canceled).

Claim 7 (canceled).

Claims 8 - 10 (canceled).

Claim 11 (canceled).

Claim 12 (canceled).